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Sheet 1 of 2

FORM PTO-1449 US Dept. of Commerce Patent and Trademark Office		ATTORNEY DOCKET NO.	SERIAL NO.
		ATMI-515	10/015,326
INFORMATION DISCLOSURE STATEMENT (use several sheets if necessary)		APPLICANT Chongying Xu, et al.	
		FILING DATE December 13, 2001	GROUP TBA

U.S. PATENT DOCUMENTS

EXAMINER INITIAL		PATENT NUMBER	ISSUE DATE	NAME	CLASS	SUBCLASS	FILING DATE IF APPROPRIATE
VM	AA	5,204,134	4/20/1993	Kirlin, et al.			
	AB	5,536,323	7/16/1996	Kirlin, et al.			
	AC	5,711,816	1/27/1998	Kirlin, et al.			
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							X (abstract only)	
VM	AQ	JP 50-111198	1/28/1974	Japan			X	

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VM	AR	Mantz, et al., "Thermolysis of Polyhedral Oligomeric Silsesquioxane (POSS) Macromers and POSS-Siloxane Copolymers", Chem. Mater., 1996, 8, pg. 1250-1259.
VM	AS	Ravi K. Laxman, Neil Hendrix Barry Arkles, Terry A. Tabler "Synthesizing Low-K CVD Materials for Fab Use" Semiconductor International, 11/1/2000

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VM Manoharan	2/24/03

EXAMINER: Initial if citation considered, whether or not citation is in conformance with MPEP § 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to the applicant.

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203 797 2544 P.12/13



Sheet 2 of 2

FORM PTO-1449	US Dept. of Commerce Patent and Trademark Office	ATTORNEY DOCKET NO.	SERIAL NO.
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VM	AT	Alfred Grill, et al., "Novel Low-k Dual-Phase Materials Prepared by PECVD", Mat. Res. Soc. Symp. Proc. Vol. 612, 2000 Materials Research Society
VM	AU	Albert Wang, et al. "TMCTS for Gate Dielectric in Thin Film Transistors", Mat. Res. Soc. Meeting 1996
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Notice of References Cited	Application/Control No.	Applicant(s)/Patent Under Reexamination	
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	Examiner	Art Unit	Page 1 of 1
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C	US-4,764,631	08-1988	Halm et al.	556/460
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M	US-			

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NON-PATENT DOCUMENTS

*	Include as applicable: Author, Title Date, Publisher, Edition or Volume, Pertinent Pages		
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*A copy of this reference is not being furnished with this Office action. (See MPEP § 707.05(a).)
Dates in MM-YYYY format are publication dates. Classifications may be US or foreign.